

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Chih-Chien Liu, et al.

Serial No: 09/546,174

Filed: April 11, 2000

For: High Density Plasma Chemical Vapor Deposition
Process

Art Unit: 1711

Confirmation No. 4793

Examiner: Sergent, Rabon A.

CERTIFICATE OF ELECTRONIC TRANSMISSION

Date of Transmission: December 20, 2007

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

I hereby certify that

- ☒ Information Disclosure Statements, with SB/08 Listing 30 References.
- ☒ authorization to charge Deposit Account the fee of \$180.00 and any deficiency of fees.

are being transmitted via electronic filing on the date indicated above to the:
Commissioner for Patents, USPTO

Date: December 20, 2007

Hogan & Hartson, LLP
1999 Avenue of the Stars, Suite 1400
Los Angeles, California 90067
Telephone: 310-785-4600
Facsimile: 310-785-4601

Lillian E. Rodriguez

Name of person transmitting papers


Signature